

**Grain Size Effects on the Reactivity of Copper Thin Films**

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Copper, thin films were prepared on Ti plates by thermal deposition from thin Cu wire. The deposition was carried out by varying distance between the source and the substrate. X-ray diffraction (XRD) and scanning electron microscopy (SEM) were used to study the morphological properties of the samples. A variation of grain sizes as a function of source to substrate distance was observed. Then the films were annealed at several temperatures in the range of 200 °C to 700 °C. Effects of annealing in air have been studied using XRD and SEM. Reactivity was not observed during annealing below 250 °C. However annealing above this temperature first produced cuprous oxide and then cupric oxide. The temperature of oxide formation was observed to be decreased function of grain size.